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Remarks:

This application was filed on 24-03-2009 as a  
divisional application to the application mentioned  
under INID code 62.

(54) **Testing apparatus**

(57) Apparatus for testing a semiconductor device under test (DUT) is provided, which comprises a driver applying a test signal to DUT; a sampler sampling an output signal outputted from DUT at a timing indicated by a strobe signal applied thereto and outputting a sample voltage; a comparator comparing the sample voltage with a reference voltage and outputting a comparison result indicating whether the sample voltage is higher than the reference voltage; a logical comparator detecting the comparison result at the timing indicated by the strobe signal and determining the quality of DUT by comparing the thus detected comparison result with an expected value.

